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Comment on: Melting behavior of SiO₂ up to 120 GPa [Andrault et al., 2020]

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I. ABSTRACT

The additional work we have done using our new laser-heating in the diamond anvil cell system 14 since the publication of [Andrault et al., 2020] leads us to the conclusion that there was a systematic 15 16 bias in the determination of temperature. First, the temperature of the W-lamp used for the calibration of the optical system was overestimated by ~22 K at 2273 K. Then, we made the assumption that hot 17 18 SiO₂ was a grey-body (constant emissivity $\varepsilon(\lambda)$), while the available measurements suggest instead that $\varepsilon(\lambda)$ of SiO₂ is similar to that of tungsten. Applying these two corrections lowers the SiO₂ melting 19 temperatures significantly. In LMV, we performed a new experimental determination of the SiO₂ 20 melting temperature, at 5000(200) K and \sim 70(4) GPa, which is well compatible with the amplitude of 21 the correction proposed. The reevaluation of the melting temperature profile does not affect largely the 22 23 interpretations or the main conclusions presented in [Andrault et al., 2020]. Within the stability field of stishovite, the melting curve still presents a relatively sharp change of slope at P-T recalculated as ~40 24 GPa and ~4800 K. It is related to a change of the melt structure. At higher pressures, the melting curve 25 is almost flat up to the subsolidus transition from stishovite to the CaCl₂-form around 85 GPa, where 26 the slope of the melting curve increases again up to ~120 GPa. We present corrected Figures and Tables 27 28 of the original publication.

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II. CALIBRATION OF THE OPTICAL SYSTEMS

On the course of the development of our new system for laser heating in the diamond anvil cell (LH-33 DAC) at the Laboratoire Magma et Volcans (LMV), we dedicated special efforts to the temperature 34 calibration. Our new LH-DAC system is very similar to that of the ID27 beamline (ESRF), which we 35 used to determine the melting properties of SiO₂ [Andrault et al., 2020]. Both system adopt the basic 36 principles established by us several years ago [Schultz et al., 2005], in particular the Schwarzschild 37 reflective objectives that present no chromatic aberrations [Giampaoli et al., 2018]. The LMV system is 38 39 optimized for simultaneous temperature measurements on both sides of the sample using the TRax software [Holtgrewe et al., 2019]. 40

41 Calibration of the optical response of the LH-DAC system is essential for the accuracy of the 42 temperature measurements. At ID27, the same tungsten lamp is used for many years. It presents a flat part on its filament, which achieves a constant temperature (e.g. 2273 K) at a given electric power. The 43 lamp was initially calibrated on a black body reference. The relationship between applied electrical 44 current and W-lamp temperature is checked regularly based on the thermal expansion of W measured 45 using X-ray diffraction [Miiller and Cezairlivan, 1990]. With a resolution on the W cell parameter $\Delta d/d$ 46 of ~1.5 10⁻⁴ [Mezouar et al., 2005], the temperature uncertainty is calculated to be ~30-40 K at 2273 K 47 [Dubrovinsky and Saxena, 1997; Miiller and Cezairliyan, 1990]. Still, there could be other experimental 48 uncertainties than thermal expansion itself. 49

In LMV, we calibrate the optical response using two techniques: (i) a Pt heating wire is calibrated at 1664 K and 1817 K based melting point of diopside and wollastonite, respectively [*Richet et al.*, 1993]. The onset of melting is indicated by the formation of a thin film of melt at the surface of the wire. Reproducing the measurement several times yields to an uncertainty of <10K. (ii) We acquired a new lamp from Pyrometer-LLC (USA), which thermal emission intensity for photons between 0.6 and 0.7 μ m was calibrated on a NIST black body standard at different temperatures between 1973 K and 2573 K. Our two methods of calibration, with Pt-wire and W-lamp, agree with each other within 10-15 K. As a result, we adopted the certified W-lamp at 2273 K to calibrate the optical response of the LMV system. We note that performing the calibration using of a W-lamp implies correcting for the emissivity function ($\epsilon(\lambda, T)$) of the W-lamp. This is not a negligible effect; a W-lamp at 2273 K presents a thermal emission spectrum similar to a grey-body (constant $\epsilon(\lambda)$) at 2358 K (Δ T=-85 K) [*Devos*, 1954].

We then performed a cross-check of the temperature calibration between the LMV and ID27 61 systems using a secondary W-lamp that was alternately installed on both systems. Its thermal emission 62 spectrum was measured at temperatures between 2244 K and 2566 K using the different optical paths 63 available on both systems. The procedure was repeated after several months. The result is a temperature 64 significantly smaller at LMV compared to ID27, for a same electrical current applied to the W-lamp. 65 66 The average temperature difference is $\sim 22(14)$ K in the range of temperature investigated, which is within the uncertainty of the W-lamp temperature based on X-ray diffraction (30-40 K). Such 67 systematic difference does not have major implication for experimental temperatures up to 2500-3000 68 K, considering that other sources of uncertainties yield to a final temperature uncertainty of ± 100 K (see 69 details in [Andrault et al., 2020]). However, it becomes more significant for the study on the melting of 70 SiO₂ that implies temperatures higher than 5000 K. 71

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III. SELECTING A PROPER EMISSIVITY FUNCTION FOR SIO2

In order to measure the sample temperature properly, one should take into account its $\varepsilon(\lambda, T)$ at high 76 temperature. Unfortunately $\varepsilon(\lambda, T)$ is poorly constrained for SiO₂, which implies making assumptions. In 77 78 [Andrault et al., 2020], we considered a constant emissivity within the 600-900 nm range of wavelength used for the temperature determination and applied the Wien law to estimate the SiO₂ temperatures. 79 However, an important observation in [Andrault et al., 2020] is a good coupling between the laser 80 radiation at $\sim 1\mu m$ and the SiO₂ sample, which is accompanied by a sample darkening in the optical 81 range at 300 K. It makes it unlikely that SiO_2 presents a perfectly flat absorption spectrum of SiO_2 82 within 600-900 nm at very high temperature. The same property should also apply for the SiO₂ 83 emissivity function, according to the Kirchhoff law correlating to each other these two functions. 84

85 Absorption spectra have been reported in the literature for several silicates including SiO₂ [Trukhin 86 et al., 2011] and Fe-bearing bridgmanite (e.g. [Keppler et al., 2008]), even though this range of wavelength is generally not the main region of interest for this type of studies. It is very interesting to 87 note that the absorption spectra present slopes comparable to the emissivity function of tungsten 88 [Devos, 1954] within the 600-900 nm range (New Fig. 9). This effect could be due to a stronger 89 90 interaction between light and electrons with increasing the light energy. This trend favors an alternative assumption to the grey-body (constant $\varepsilon(\lambda)$); namely a sample $\varepsilon(\lambda, T)$ similar to that of the W-lamp at 91 the calibration temperature of ~2273 K. This hypothesis was largely used in the past in the Mineral 92 Physics community. This implies a significant correction to the SiO₂-sample temperature; e.g. -85 K for 93 a refined grey-body temperature of 2358 K. 94

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IV. CORRECTED RESULTS

99 We reinvestigate the sample temperatures reported in [Andrault et al., 2020] applying the correction of 22 K to the tungsten lamp and the same $\epsilon(\lambda, T)$ for SiO₂ and the W-lamp. We are conscious that the 100 latter has consequences; A temperature correction may be applied in the future, when $\varepsilon(\lambda, T)$ of SiO₂ 101 will be better constrained. To calculate the updated sample temperatures (T_{updat}), we consider that the 102 optical response of the ID27 LH-DAC system had not been evaluated properly, considering a W-lamp 103 at 2295 K instead of 2273 K. For a dozen of temperatures between 1500K and 7000K (published 104 temperatures; T_{pub}), we calculate: (i) The grey-body function of the sample at T_{pub} : GB(T_{pub}). (ii) The 105 grev-body functions of the W-lamp at 2295 K and 2273 K: GB(T_{lamp}-old) and GB(T_{lamp}-new), 106 respectively. (iii) The sample thermal emission: TE=GB(T_{pub})*GB(T_{lamp}-new)/GB(T_{lamp}-old). (iv) Then, 107 108 we refine T_{updat} based on TE assuming $\epsilon(\lambda, T)$ of SiO₂ similar to that of W. The use of Wien or Planck laws is indifferent. It yields a polynomial relation between T_{pub} and T_{updat} : $T_{updat} = -26 + 1.017 T_{pub} - 1.017 T_{pub}$ 109 2.316 10⁻⁵ T_{pub}². 110

The uncertainty of 14K on the temperature correction of 22(14) K at 2273 K induces uncertainties of 111 25 or 113 K on the T_{updat} sample temperature at 2816 or 6163 K, respectively. This is significantly 112 smaller than the accuracy of the melting curve temperature determination, which is the temperature 113 114 difference between data points at which the sample was found solid or liquid (blue and red dots in Fig. 115 3-corr, respectively).

116 We reevaluated the sample pressures as well, because we had considered a pressure increase due to 117 some isochoric heating (see [Andrault et al., 2020]). The correction yields significant changes in the melting curve of SiO₂ (Table 1-corr; Fig. 3-corr). For example, the maximum (P,T) investigated are 118 recalculated to be ~117 GPa and ~6200 K, instead of ~120 GPa and ~7000 K in [Andrault et al., 2020]. 119 120

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V. NEW EXPERIMENTAL MEASUREMENT

To check the robustness of the proposed temperature correction, we performed a new determination 124 125 of the SiO₂ melting temperature using the LH-DAC system of LMV. The sample consisted of two thin pellets of SiO₂ between which we deposited a little bit of Si-powder to facilitate absorption of the ~ 1 126 µm laser radiation at low temperature. This is similar as the second series of experiments in [Andrault et 127 al., 2020]. Melting criteria were based on (i) analysis of the relation between the sample temperature 128 and the laser power and (ii) optical observation of the recovered sample (New Fig. 10). For a nominal 129 130 pressure of 49 GPa (at 300K), temperature increased progressively with laser power until a flattening of this relationship. Above 140 W of laser power, we observed temperature fluctuations because the SiO₂ 131 melt, which was produced sporadically, did not absorb enough laser radiation to maintain the 132 temperature in its stability field. The highest temperature that we could reach up to 180 W is 4950(200) 133 134 K, which we associate to the highest possible temperature for solid SiO₂ at this pressure. Steady state production of liquid-SiO₂ in this sample (as performed in [Andrault et al., 2020]) would require even 135 more laser power. The sample pressure at \sim 4950 K is estimated to 70(4) GPa after correction for the 136 thermal pressure. The recovered sample presents circular figures of absorption that are typical of 137 138 melting corona observed on several types of sample (New Fig. 10).

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VI. DISCUSSIONS

143 Global trends and main conclusions of [Andrault et al., 2020] are not significantly affected by the temperature correction. We detail below the changes that apply: 144

- The steep SiO₂ melting curve extends to ~40 GPa and the Clapeyron slope between stishovite and 145 146 the low-density melt (LDM) is ~76 K/GPa (Table 2-corr, New Table 3). This corresponds to similar 147 temperatures than reported in some theoretical calculations [Belonoshko and Dubrovinsky, 1995; Usui and Tsuchiya, 2010]. On this segment, our data plot more linearly than any other melting studies, 148 149 including the experimental work [Shen and Lazor, 1995]. As mentioned in [Andrault et al., 2020], this observation is compatible with minor changes in the LDM structure up to ~40 GPa. 150

- The triple point between stishovite, LDM and high-density melt (HDM) is found at ~40 GPa and 151 ~4800 K. We refine a LDM-HDM volume change of -4.21(20) instead of -4.02(20) cm³/mol in 152 [Andrault et al., 2020]. 153

- A relatively flat melting curve extends from 40 to 85 GPa and 4800 to 5200 K with a Clapeyron 154 slope of 9 GPa/K. The associated stishovite-HDM volume of fusion is 0.56(13) cm³/mol, which 155 corresponds to 4.0(0.9)% of the stishovite volume. This is ~10 times smaller than the stishovite-LDM 156 volume change of $\sim 4.77 \text{ cm}^3/\text{mol}$. 157 158

As a result, the volume change between LDM and HDM melts is ~26%.

159 -Above 85 GPa, the Clapeyron slope increases again to ~31 GPa/K. At the highest pressure of this 160 study, ~117 GPa, the melting point of SiO₂ in its CaCl₂-form plots at ~6200 K, which is just in-between temperatures reported at each side of the solid-liquid transition of shocked quartz [Akins and Ahrens, 161 162 2002] (Fig. 3-corr).

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New Figure 9: Normalized absorption and emissivity functions. Emissivity functions of a tungsten
wire [*Devos*, 1954; *Larrabee*, 1959] are plotted together with absorption spectra of SiO₂ [*Trukhin et al.*,
2011] and Fe-bearing bridgmanite [*Keppler et al.*, 2008], within the range of wavelength (600-900 nm)
used for pyrometric determination of temperature in our LH-DAC experiments.



New Figure 10: (A) Optical microphotograph showing circular figures around the melted zone of the 224 recovered sample. The external diameter is ~60 µm. (B) Relationship between sample temperature 225 226 and laser power: A maximum temperature of 4950(200) K was reached on both sample sides for a laser power up to 180 W, even though higher temperatures are predicted from the linear relationship 227 between laser power and temperature up to ~120 W (dashed line). Between 140 and 180 W, 228 229 temperature flucturations occured because the melt, which is produced sporadically at temperatures higher than ~4950 K, does not absorb enough the laser radiation to maintain the sample temperature in 230 231 its stability field (AV for front side and AR for rear side of the sample).

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224	Table 1 corrected	נאספנים	Tama	D(hish_T)	Teme	Teme
234	Table I correcteu.	F(SOOK)	Temp.	F(nigh-1)	Temp	remp
235		GPa	K	GPa	solid	Melt
236		12	2816	14	2728	2904
220		16	3877	25	3754	4000
237		19	3836	28	3671	4000
238		19	4751	37	4636	4866
239		19.5	4713	37	4519	4713
240		20	4866	40	4866	4942
241		21	4942	42	4866	5093
241		21.5	4558	38	4479	4713
242		21.5	4401	36	4321	4479
243		26	4866	46	4713	5018
244		36	4866	55	4713	5018
245		39	5018	60	4790	5093
246		45	5093	66	5018	5241
240		54	5018	74	4790	5093
247		76	5605	102	5533	5676
248		76	5533	101	5461	5605
249		85	6163	117	6095	6231
250		85	5957	114	5888	6026
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Transition	Press.	Temp.	dT/d	Р	ΔS	ΔV		Vstis	h	Vcoe	s	VLD	M	VHDM	[ΔV/V	
considered	GPa	K	K/GI	Pa	mol/K	cm3/m	01	cm3/m	101	cm3/m	101	cm3/m	ıol	cm3/mo	1		
C => S	15	2900	312	a	-15.3 a	-4.77	b	14.69	g	19.46	h					-28% k	
C => LDM	15	2900			74.9 d	0.00	e			19.46	h						
S => LDM	15	2900	76	*	62.7 b	4.77	g	14.69	g			19.5	i			28% k	
S => HDM	40	4800	9	*	77.7 d	0.69	b	13.63	g					14.3	j	4.9% k	
LDM=>HDM	40	4800			-15.0 c	-4.08	f					18.4	i	14.3	j	-25% k	
S => HDM	40	4800	9	*	62.7 d	0.56	b	13.63	g					14.2	j	4.0% k	
LDM=>HDM	40	4800			0.0 c	-4.21	f					18.4	i	14.2	j	-26% k	
S => HDM	40	4800	9	*	47.7 d	0.42	b	13.63	g					14.1	j	3.1% k	
LDM=>HDM	40	4800			15.0 c	-4.34	f					18.4	i	14.1	j	-27% k	

C, S, LDM and HDM stand for Coesite, Stishovite, low-density and high-density SiO2 melts

*, this study

a, from Akaogi et al. (2011)

Table 2 corrected:

b, calculated based on the Clapeyron relation $dT/dP{=}\Delta V{/}\Delta S$

c, value assumed to be -15, 0 or 15 J/molK (see text)

d, derived from Clapeyron relations around the (C, S, LDM) or (C, LDM, HDM) triple points

e, derived from the flat melting curve of coesite between 9 and 14 GPa (Zhang et al., 1993)

f, calculated using ΔV =VHDM-VLDM

g, calculated at the considered P-T conditions using the EoS of Wang et al. (2012)

h, calculated using Vcoes=Vsti+ Δ V(C-S)

i, calculated using VLDM=Vsti+ Δ V(LDM-S)

j, calculated using VHDM=Vsti+ Δ V(HDM-S)

k, ΔV of the transition normalized to the mean value between the two phases considered

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256 <u>New Table 3</u>: Conditions (P-T) of the triple points and maximum conditions performed in this study.
 257 We also report the Clapeyron slopes between these points taken 2 by 2.

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	Pressure	Temperature	Slope
	GPa	K	K/GPa
Triple (C,S,LDM)	15	2900	
Triple (S,LDM,HDM)	40	4800	76
Triple (S,CaCl2,HDM)	85	5200	9
P-T max	117	6200	31